

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Takahiro Yamaguchi et al.)	Group Art Unit
)	
Serial No.	:	New Application)	
)	
Filed	:	Concurrently Herewith)	
)	
For	:	POSITION DETECTION)	
		APPARATUS, POSITION)	
		DETECTION METHOD,)	
		ELECTRONIC PART CARRYING)	
		APPARATUS, AND ELECTRONIC)	
		BEAM EXPOSURE APPARATUS)	
)	
Examiner	:	Unknown)	
)	

INFORMATION DISCLOSURE STATEMENT

Hon. Commissioner
of Patents and Trademarks
Washington, D.C. 20231

Dear Sir:

Enclosed is a form PTO-1449 listing two prior art references relevant to the above-identified application. A copy of the two references and English abstracts is also enclosed herewith.

These prior art references are cited in the International Search Report issued by Japanese Patent Office in the international stage of this case. A copy of the English version of International Search Report is also attached herewith. Since all of the prior art references are non-English documents, an English abstract is attached to each of the references. The prior art references enclosed are:

(1) Japanese Patent Laid-Open Publication No. 07-159056
is relevant to the present invention because it discloses a

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process of radiating electron beam on a semiconductor
integrate circuit device.

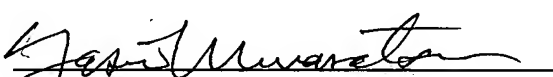
(2) Japanese Patent Laid-Open Publication No. 10-134184
is relevant to the present invention because it discloses a
pattern detecting device to detect whether a particular
pattern is part of a registered pattern.

Applicant respectfully requests that the prior art references
submitted be considered in the substantive examination of this
application.

Respectfully submitted,

MURAMATSU & ASSOCIATES

Dated: 11/15/2003

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IDS-RY04.001
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Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Complete if Known	
				Application Number	
				Filing Date	
				First Named Inventor	
				Group Art Unit	
				Examiner Name	
Sheet	1	of	1	Attorney Docket Number	RYUKA.004AUS

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Examiner Signature		Date Considered	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

Burden Hour Statement: This form is estimated to take 2.0 hours to complete. Time will vary depending upon the needs of the individual case. Any comments on the amount of time you are required to complete this form should be sent to the Chief Information Officer, U. S. Patent and Trademark Office, Washington, DC 20231.. **DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO:** Assistant Commissioner for Patents, Washington, DC 20231.